

## Supplementary

### Ellipsometry study of PLD based temperature controlled thin film depositions of CdSe on ITO substrates

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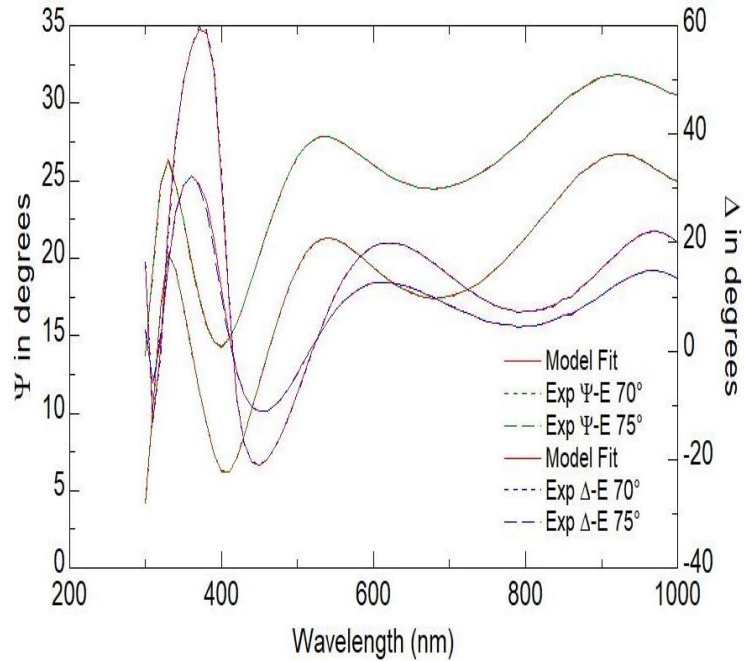


Fig.1. Measured and fitted Psi and Delta vs. wavelength of the ITO two sub-layer substrate used for CdSe thin films deposition

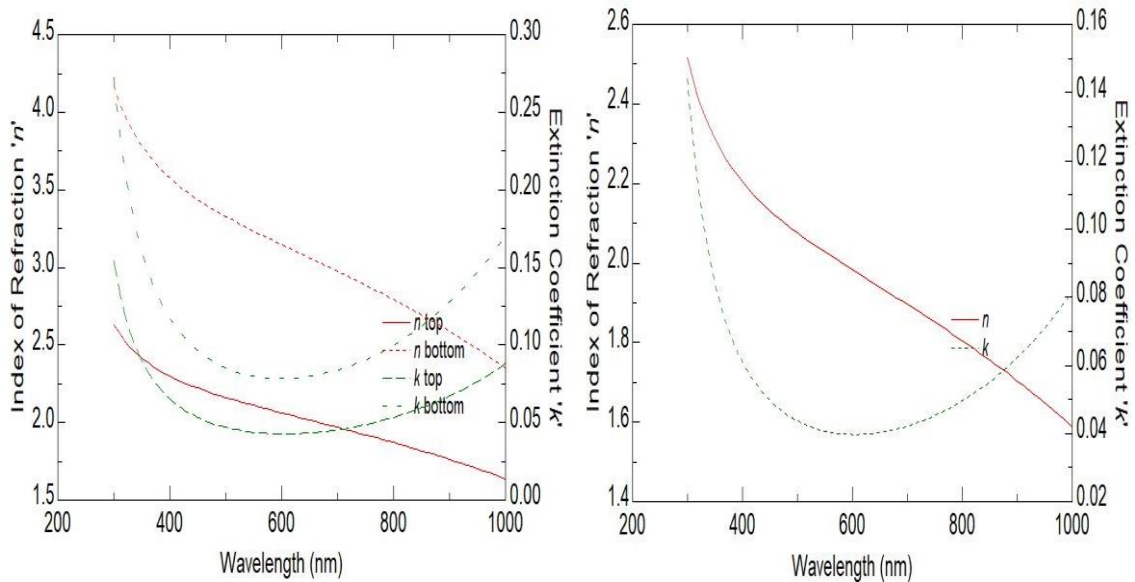


Fig.2 (Left) The Optical functions ( $n$  and  $k$ ) of the ITO upper 130nm graded layer; (Right) the bottom 0.7 mm layer of the ITO substrate